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CHANGES TO THE

RECTIFIER

- (a) Remove circline light used for illumination of the fiducial marks in order to prevent vignetting of the negative field in extreme setting positions. Other suitable illumination means shall be provided.
- (b) Replace both folded bellows between the negative stage housing and the lens by lightweight cloth material in order to prevent vignetting.
- See that design prohibits instrument reflection (c) to reach easel surfaces.
- (d) Provide index marks on the program cylinder and pilot warning light on the control panel, indicating setting of card reader.
- (e) Provide metal clips along upper edges of both easels to clamp film material.
- (f) Provide 10" x 10" opal diffusing screen attachable to pressure plate door of negative stage.
- (g) Provide 10" x 10" heat reflecting glass to be attachable to pressure plate door of negative stage.
- (h) Relocate vernier light of negative stage circle to make vernier readable.
- (i) Provide clamp for the film stage Y motion that can be easily operated. Clamp action shall not change setting by more than 0.05 millimeters.
- (j) Rework object stage horizontal and vertical castings, as necessary, to avoid vignetting on the second stage easel.
- / *(k) Extend the first easel sufficiently to allow higher tilts to be used on the first stage. 18 inch EF to 650 on single stage.
- /*(1) If available, provide PXA ballast that will allow a rectification to be made at the maximum tilt while making only one pass.
 - (m) Provide suitable coded connectors on the base of the rectifier.

*Additional cost unknown

K- no addl wet. l- none available - no charge

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